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(71) Applicant (for all designated States except US): TOKYO OHKA KOGYO CO., LTD. [JP/JP]; 150, Nakamaruko, Nakahara-ku, Kawasaki-shi, Kanagawa, 211-0012 (JP).

(72) Inventors; and

- (75) Inventors/Applicants (for US only): WASHIO, Yasushi [JP/JP]; c/o 150, Nakamaruko, Nakahara-ku,, Kawasaki-shi, Kanagawa, 211-0012 (JP). SAITO, Koji [JP/JP]; c/o 150, Nakamaruko, Nakahara-ku,, Kawasaki-shi, Kanagawa, 211-0012 (JP).
- (74) Agents: TANAI, Sumio et al.; 2-3-1, Yaesu, Chuo-ku,, Tokyo 104-8453 (JP).

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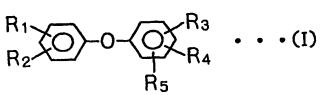
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(54) Title: DEVELOPER COMPOSITION FOR RESISTS AND METHOD FOR FORMATION OF RESIST PATTERN



(57) Abstract: To provide a developer composition for resists, capable of improving dimensional controllability of a resist pattern. The developer composition for resists comprises an organic quaternary ammonium base as a main component, said developer composition further comprising an anionic surfactant represented by the following general formula (I), and SO₄² the content of SO₄² being from 0.01 to 1% by mass. Formula (I). In the

formula, at least one of R_1 and R_2 represents an alkyl or alkoxy group having 5 to 18 carbon atoms and the other one represents a hydrogen atom, or an alkyl or alkoxy group having 5 to 18 carbon atoms, and at least one of R_3 , R_4 and R_5 represents an ammonium sulfonate group or a sulfonic acid-substituted ammonium group and the others represent a hydrogen atom, an ammonium sulfonate group or a sulfonic acid-substituted ammonium group.

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